METHOD OF MANUFACTURING A SUBSTRATE FOR A MAGNETIC DISK

Abstract of the Disclosure:

A magnetic disk substrate manufacturing method of this invention includes a main surface polishing process that polishes disk-shaped glass substrates by the use of a polishing machine having a carrier pressed between a pair of polishing surface plates and adapted to make an orbital motion while rotating on its axis in a state of holding the disk-shaped glass substrates. In the polishing machine, the carrier is placed in a state where a plate-like member is disposed on one side of main surfaces of the disk-shaped glass substrate, so that only the other side of the main surfaces of the disk-shaped glass substrate is polished while allowing the one side of the main surfaces of the disk-shaped glass substrates to be a non-polishing main surface.

FIGURE 1